# Current-voltage analytical model and multiobjective optimization of design of a short channel gate-all-around-junctionless MOSFET

F. Pezzimenti<sup>1\*</sup>, H. Bencherif<sup>2,3</sup>, A. Yousfi<sup>2</sup>, and L. Dehimi<sup>3</sup>

<sup>1</sup>DIIES, Mediterranea University of Reggio Calabria, Reggio Calabria, Italy.

<sup>2</sup>LAAAS, Department of Electronics, University Mostefa Benboulaid - Batna 2, Algeria.

<sup>3</sup>Laboratory of Metallic and Semiconductor Materials, University of Biskra, Algeria.

\*fortunato.pezzimenti@unirc.it

#### Abstract

In this paper we investigate the optimized design of a short channel gate-all-around-junctionless (GAAJ) metaloxide-semiconductor field-effect-transistor (MOSFET), including the source-drain extensions, by means of genetic algorithm solutions applied to a compact current-voltage analytical model. In fact, due to the complex device structure, it seems useful to exploit a metaheuristic-based approach to search the optimal combination of the fundamental geometrical and physical parameters that lead to an improved performance. Through this analysis, different parameter constraints are imposed for the calculation of specific objective functions. In particular, for a fixed gate-drain bias level, the task pursues the maximization of the drain current and cut-off frequency while limiting the short channel (SC) effects. The MOSFET series resistance is also evaluated in the transition region of the  $I_d - V_{gs}$  characteristics which appear, however, strongly affected by SC effects. The accuracy of the model is verified by comparison with experimental data reported in literature.

Keywords: GAAJ MOSFET; short channel; drain current; series resistance; cut-off frequency.

#### 1. Introduction

In modern power electronics, the continuous geometrical downscaling of the metal-oxide-semiconductor (MOS) structures is needful for the realization of high-performance MOS field-effect-transistors (FETs) to be used in both analog and digital fields. However, the ultra large scale of integration for MOSFET technology leads to undesired short channel (SC) effects, which penalize the device performance mainly in terms of carrier saturation velocity, leakage current, and power dissipation. To overcome these technological issues, different silicon (Si)-based FETs have been suggested and characterized in literature [1-6]. In particular, gate-all-around-junctionless (GAAJ) MOSFETs have been recognized as attractive structures for high performance devices by considering their improved carrier transport mechanisms, outstanding scalability, and leakage current (gate voltage) controllability [7-10]. Moreover, GAAS structures, avoiding the realization of abrupt p-n junctions, are in principle well suited to increase the device immunity to SC effects and therefore the MOSFET current capabilities [11-14]. However, the design of a GAAS MOSFET, which can involve also pin and/or Schottky structures, still requires the deployment of rigorous modelling efforts based either on empirical computations or analytical (numerical) simulations to meet specific application constraints [15-22].

In this paper, the optimized design of a SC GAAJ MOSFET including source-drain extensions is investigated by combining a compact current-voltage analytical model and a multiobjective genetic algorithm (MGA) for the

calculation of the geometrical and physical parameters that improve the device performance. In particular, starting from a reference device, the obtained results provide significant improvements in terms of important figures of merit (FOM) such as the drive current, series resistance, and cut-off frequency. The theoretical background for the computation methodology is also presented.

The analytical model taken into account has been validated with numerical simulations in a recent manuscript of ours where preliminary results on different GAAJ structures have been investigated and the need of an exhaustive design optimization approach has been introduced [23].

# 2. GAAJ MOSFET structure

A schematic 2D cross-sectional view of the cylindrical GAAJ MOSFET considered in this work is shown in figure 1 along with the notation adopted for the fundamental geometrical parameters.



Figure 1. Schematic 2D cross-sectional view of the considered GAAJ MOSFET.

In more detail,  $t_{ox}$  is the oxide thickness, *R* is the channel radius, *L* is the channel length (gate length), and  $L_{ext}$  is the extension length of the drain (source) region. In addition, we can note that the source and drain extensions are assumed with a doping level higher than that of the channel-body region. In fact, the use of a uniform doping concentration limits the drain current introducing a severe series resistance related to the extension regions [24]. The device reference parameters used as entry data for modelling are listed in Table 1.

The doping concentrations are in accordance with theoretical and experimental results reported in literature [24-26]. A radius in the inferior limit of 7.5 nm is assumed to prevent quantum phenomena as suggested in [27] and references therein. Also, lower values of R tend to increase the SC effects.

Channel radius, R (nm)	7.5
Silicon oxide thickness, $t_{ox}$ (nm)	2
Metal work function, $\Phi_m$ (eV)	5.27
Channel length, $L$ (nm)	30
N-type channel doping, $N_d$ (cm <sup>-3</sup> )	1×10 <sup>19</sup>
Extension length, $L_{ext}$ (nm)	10
N-type extension doping, $N_{dext}$ (cm <sup>-3</sup> )	5×10 <sup>19</sup>

Table 1. GAAJ MOSFET reference parameters.

#### 3. Current-voltage analytical model

Starting from Poisson equation in cylindrical coordinates, the GAAJ MOSFET drain current equation in on-state with grounded source can be expressed as follows [14]:

$$I_{d} = 2\pi \frac{R \mu_{n} V_{T}}{L} (F(V_{i}) - F(V_{i} + V_{ds}))$$
(1)

where, labelled  $V_i$  the built-in potential at the source/channel junction ( $V_i = V_T \ln(N_{dext}/n_i)$  [27,28]) and  $V_{ds}$  the applied bias at the drain contact, the terms F(V) are in the form [28]

$$F(V) = \frac{(Q_{cp} + C_{OX}V_T) Q_{mob}(V)^2}{2Q_{cp}C_{OX}V_T} + 2Q_{mob}(V) - CQ_{mob}(V) \ln\left[1 + \exp\left(\frac{Q_{mob}(V) - Q_{fix}}{2CQ_{cp}}\right)\right] + Q_{fix} \ln\frac{Q_{mob}(V) - Q_{fix}}{2Q_{cp}\exp\left(\frac{Q_{mob}(V) - Q_{fix}}{2Q_{cp}} - 1\right)}$$
(2)

Here,  $V_T$  is the thermal voltage,  $Q_{fix} = q N_d R/2$  refers to the fixed charges in the channel region,  $C_{OX} = \varepsilon_{OX} / R \ln(1 + t_{OX} / R)$ ,  $Q_{cp} = 2\varepsilon_0 \varepsilon_{Si} V_T / R$ , and the mobile charge  $Q_{mob}(V)$  is given by an accurate expression for SC devices, i.e.

$$Q_{mob}(V) = \frac{Q_{cp}C_{OX}V_{T}}{(Q_{cp} + C_{OX}V_{T})}LW \left[ \frac{(Q_{cp} + C_{OX}V_{T})Q_{fix}Q_{cp}}{Q_{cp}C_{OX}V_{T}} \frac{\exp\left(\frac{Q_{m}^{0} - Q_{fix}}{Q_{cp}}\right) - 1}{Q_{m}^{0} - Q_{fix}} \exp\left(v + \frac{Q_{fix}}{fQ_{cp}}\right) \right]$$
(3)

where LW stands for the Lambert function approximation [29]

$$LW(z) = \ln(1+z)\left(1 - \frac{\ln(1+\ln(1+z))}{2 + \ln(1+z)}\right) , \qquad (4)$$

$$f = 1 + \frac{Q_m^0}{5Q_{fix}} \exp(-\frac{Q_m^0}{Q_{fix}})$$
, and  $v = (V_{gs} + V_{fb} + Q_{cp} / C_{OX} - V) / V_T$  is a term that contains all the voltage

dependences. In particular,  $V_{fb} = \Phi_{ms} + V_T \ln(N_d/n_i)$  is the flat-band voltage depending on the channel doping concentration, the intrinsic carrier concentration  $(n_i)$ , and the difference between the metal gate and semiconductor work-function, namely  $\Phi_{ms} = \Phi_m - \Phi_s = \Phi_m - (\chi + E_g/2q)$  [14,30] where  $\chi$  and  $E_g$  are the electron affinity and bandgap of Si, respectively. Finally, in (3),  $Q_m^0$  is given by [14]

$$Q_m^0 = C_{OX} V_T LW \left\{ \frac{Q_{fix} Q_{cp}}{C_{OX} V_T} \left[ \frac{1 - \exp\left(\frac{Q_{fix} - Q_{m1}}{Q_{cp}}\right) \right]}{Q_{m1} - Q_{fix}} \right\} \exp(\nu)$$
(5)

where

$$Q_{m1} = \frac{Q_{cp}C_{OX}V_T}{(Q_{cp} + C_{OX}V_T)}LW \left[ \frac{(Q_{cp} + C_{OX}V_T)Q_{fix}Q_{cp}}{Q_{cp}C_{OX}V_T} \frac{\exp\left(\frac{Q_{fix} - Q_{m2}}{Q_{cp}}\right)}{Q_{m2} - Q_{fix}} \exp(v) \right],$$
(6)

$$Q_{m\,2} = 2C_{OX} V_T LW \left[ \frac{\sqrt{Q_{fix} Q_{cp}}}{C_{OX} V_T} \exp(\nu/2) \right].$$
<sup>(7)</sup>

The doping dependent carrier mobility in (1) is modelled by the Caughey-Thomas equation at room temperature:

$$\mu_n = \mu_{\min} + \frac{\mu_{\max} - \mu_{\min}}{1 + \left(\frac{N_d}{N_{crit}}\right)^{\alpha}}$$
(8)

where  $N_{crit}$  is the doping concentration reference parameter at which the mobility is halfway between its maximum and its minimum value [31,32]. For a Si-based device, we have  $\mu_{max} = 1400 \text{ cm}^2/\text{Vs}$ ,  $\mu_{min} = 688 \text{ cm}^2/\text{Vs}$ ,  $\alpha = 0.71$ , and  $N_{crit} = 1 \times 10^{18} \text{ cm}^3$ . In addition, to account for the mobility degradation in a SC device due to the carrier saturation velocity ( $v_{sat} = 1 \times 10^7 \text{ cm/s}$ ), an effective carrier mobility  $\mu_{eff}$  is assumed as follows [33,34]

$$\mu_{eff} = \frac{\mu_n}{\left[1 + \left(\frac{\mu_n V_{deff}}{L v_{sat}}\right)^{\beta}\right]^{\frac{1}{\beta}}}$$
(9)

where  $\beta = 2$  for electrons, and  $V_{deff}$  is the effective drain voltage which saturates the drain current at a value  $V_{dsat}$  calculated as [28]:

$$V_{dsat} = \frac{V_x}{\frac{V_x}{V_{crit}} + 1}$$
(10)

by assuming

$$V_x = \frac{Q_{mob}(0)}{C_{OX}} + \frac{V_{crit}}{\frac{V_{crit}}{2V_T} - 1}$$
(11)

$$V_{crit} = 2\frac{v_{sat}}{\mu_n}L \quad . \tag{12}$$

In accordance with [28],  $V_{deff}$  is in the form:

$$V_{deff} = V_{dsat} - V_{dsat} \frac{\ln\left\{1 + \exp\left[B\left(1 - \frac{V_{ds}}{V_{dsat}}\right)\right]\right\}}{\ln(1 + \exp B)}$$
(13)

where B is a smoothness parameter equal to 3 for SC devices.

# 4. Theoretical basis for MGAs

Multiobjective genetic algorithms are a flexible approach for the optimal solution of constrained and unconstrained problems where different objective functions must be evaluated simultaneously [35-39]. These techniques allow the selection of a suitable set of solutions according to the problem application field and provide a simple implementation also dealing with a huge quantity of information. Genetic algorithms take their origin from natural evolution of species. In other words, starting from an initial population, they randomly select individuals and create new generations called children. This procedure is repeated along for different generations to meet the stopping criteria that produce the optimal solution. A simplified flowchart for MGAs is shown in figure 2. Selection, crossover, and mutation are the fundamental operations imposed on a certain generation to allow the procedure to evolve.

Using the MGA terminology, the initial population corresponds to the GAAJ MOSFET geometrical and physical parameters, such as the oxide thickness, channel radius, channel length, and doping concentrations, which play a key role in determining the effective device performance.

Further details about the MGA approach and the simulation models for MOSFETs are provided in recent author manuscripts [41-44].



Figure 2. Flowchart for MGA.

### 5. Results and discussion

# 5.1 Reference device

For the GAAJ MOSFET described in Table 1, the  $I_d$ - $V_{gs}$  curves calculated at two different drain voltages (i.e.,  $V_{ds} = 1 \text{ V}$  and  $V_{ds} = 0.05 \text{ V}$ ) are shown in figure 3. In accordance with [24], the device is supposed to work at  $V_{gs} < 2 \text{ V}$  to avoid starting an overestimation of  $I_d$  by neglecting the anomalous distributions of the potential in the MOSFET active regions for high gate voltages.



Figure 3.  $I_d$ - $V_{gs}$  curves for the GAAJ MOSFET in Table 1.

As we can see, above the threshold voltage, the drain current increase is strongly limited by the combined effects

of the device series resistance and carrier saturation velocity in the channel region. The  $I_d$ - $V_{ds}$  characteristics for different values of  $V_{gs}$  are plotted in figure 4.



Figure 4. *Id*-*Vds* curves for the GAAJ MOSFET in Table 1.

In figure 4, the dashed line marks the transition region determined by the carrier saturation velocity. For instance, for  $V_{gs} = 1.5$  V and  $V_{ds} = 1$  V the drain current is close to the saturation value of 50  $\mu$ A, which corresponds to a series resistance on the order of 3.53  $\Omega \times \mu m^2$ . The series resistance behaviour as a function of  $V_{gs}$  in the  $V_{ds}$  transition region is shown in figure 5. This behaviour mainly depends on the effective device length (i.e.,  $L+2L_{ext}$ ) and doping concentration in the drain and source extensions.



Figure 5. Series resistance behaviour as a function of  $V_{gs}$  in the transition region of the  $I_d$  -  $V_{ds}$  characteristics.

The transconductance is another important FOM that determines the ability of the device to amplify a signal. It is

calculated by the first derivative of the drain current, i.e.  $g_m = \partial I_{ds} / \partial V_{gs}$ . The  $g_m$  curve as a function of  $V_{gs}$  for  $V_{ds} = 1$  V and  $V_{ds} = 0.05$  V (deep triode region) is shown in figure 6.



Figure 6. Transconductance characteristics for the GAAJ MOSFET in Table 1. The inset shows the transconductance generation factor (TGF) around the threshold voltage for  $V_{ds} = 1$  V.

High values of  $g_m$  can be achieved when  $V_{ds}$  rises and  $V_{gs}$  is firmly above the device threshold voltage  $(V_{gs} \ge 0.3 \text{ V for } V_{ds} = 1 \text{ V})$ . A  $g_m$  peak close to 51  $\mu$ AV<sup>-1</sup> is calculated for  $V_{ds} = 1 \text{ V}$  and  $V_{gs} = 1.5 \text{ V}$ . This value of  $g_m$  corresponds to a cut-off frequency of 220 GHz, estimated with the standard expression

$$f_c = \frac{g_m}{2\pi C_G} \tag{14}$$

assuming, for the sake of simplicity, the total amount of the input capacitance  $C_G$  equal to  $C_{OX}$ . In fact, although  $C_G$  is a term strictly dependent on the bias level, for the considered operating voltages  $V_{gs} = 1.5$  V and  $V_{ds} = 1$ V, this appears as a reasonable approximation. However, additional capacitance contributions neglected in this first-level analysis could reduce the value of  $f_c$  and therefore it has to be considered as an upper limit for the device. Another significant parameter is the transconductance generation factor (TGF) which aids to fix the role of the drain current in determining  $g_m$ . In fact, TGF is defined as the ratio  $g_m/I_d$  and it can be evaluated starting from the weak inversion regime, namely for a  $V_{gs}$  around the threshold voltage, as shown in the inset of figure 6 for 0.25V $\leq V_{gs} \leq 0.75$ V and  $V_{ds} = 1$  V. In particular, we TGF values are on the order of 1 V<sup>-1</sup> confirming that the

#### 5.2 Design optimization

proposed MOSFET could operate efficiently at low supply voltages.

The optimization of the GAAJ structure is a complex task due to the interrelated geometrical and physical parameters that influence the device performance. A systematic investigation aimed to find the optimal design parameters can be made by using the MGA approach introduced previously. In more details, in this work the MGA-based optimization framework deals with the statement of three objective functions, namely the drain

current, the cut-off frequency, and the subthreshold slope (SS), which are in the form of  $I_d(X)$ ,  $f_c(X)$ , and SS(X) where  $X = (R, L, L_{ext}, t_{ox}, \Phi_m, N_d, N_{dext}, V_{gs}, V_{ds})$  is a vector of device parameters. Therefore, for each fixed gate-drain bias level, the task is related to the following criteria: maximize the drain current and cut-off frequency while minimizing the SS difference calculated with respect to the ideal value of 60 mV/dec in order to limit the SC effects. Proper constraints that define each parameter within a specific range of values are imposed during the computations as summarized in Table 2.

<i>R</i> (nm)	7 - 14
L (nm)	20 - 30
$L_{ext}$ (nm)	8.5 - 10
$t_{ox}$ (nm)	2 - 4
$\Phi_m ({ m eV})$	4.6 - 5.27
$N_d$ (cm <sup>-3</sup> )	1×10 <sup>18</sup> - 5×10 <sup>19</sup>
N <sub>dext</sub> (cm <sup>-3</sup> )	1×10 <sup>19</sup> - 1×10 <sup>20</sup>
$V_{gs}\left(\mathrm{V} ight)$	0 - 1.75
Vds (V)	0 - 1

Table 2. Range of values in defining the vector X.

Referring to the MGA flowchart in figure 2, we can state that the number of variables is 9 (dimension of X), and the assumed population size is 100. Finally, for evolving during consecutive generations the genetic operations are tournament-type selection, constraint dependent crossover, and scattered mutation. In addition, to optimize the procedure computational time the weighted sum approach is used in order to incorporate the different objective functions in a mono-objective function given by

$$F(X) = w_1 f_c + w_2 I_d + w_3 SS$$
(15)

where the optimal solution is calculated setting the no-preference method for the weighting factors, i.e.  $w_1 = w_2 = w_3 = 0.333$ . The behaviour of F(X) as a function of the evolving generations is shown in figure 7.



Figure 7. F(X) behaviour as a function of the evolving generations.

The convergence occurs in the 26<sup>th</sup> generation requiring a computational time of about 15 min by using an updated personal computer. Then, the achieved fitness function corresponds to the optimal solution that provides the best device performance.

The optimized design of the GAAJ MOSFET and the extracted SC and FOM parameters are summarized in Table 3. Here, the results of the reference device in Table 1 are also reported for comparison. In particular, the value of the drain induced barrier lowering (DIBL) is calculated as ratio of the threshold voltage reduction to the applied change in  $V_{ds}$  assuming  $V_{ds} = 0.05$  V and  $V_{ds} = 1$  V, respectively. Similarly, the subthreshold slope is defined as the change in  $V_{gs}$  that must be applied in the subthreshold regime to determine a drain current increase of one decade starting from the off-state current calculated for  $V_{gs} = 0$  V. The obtained value of *SS* is in the limit of 80 mV/dec and it is consistent with literature data [24,45].

	Reference device	Optimized device
Design parameters		
Channel radius, <i>R</i> (nm)	7.5	11
Silicon oxide thickness, <i>t</i> <sub>ox</sub> (nm)	2	2
Metal work function, $\Phi_m$ (eV)	5.27	4.6
Channel length, L (nm)	30	20
N-type channel doping, $N_d$ (cm <sup>-3</sup> )	1×10 <sup>19</sup>	2.5×10 <sup>18</sup>
Extension length, <i>L<sub>ext</sub></i> (nm)	10	8.6
N-type extension doping, N <sub>dext</sub> (cm <sup>-3</sup> )	5×10 <sup>19</sup>	7.5×10 <sup>19</sup>
SC effects (a) $V_{ds} = 1$ V		
Threshold voltage (V)	0.3	0.25
Off-state current density ( $\mu A/\mu m^2$ )	2.26	2.63
DIBL (mV/V)	315	336
Subthreshold slope (mV/dec)	75	79
FOM (a) $V_{gs} = 1.5$ V and $V_{ds} = 1$ V		
On-state current density (mA/µm <sup>2</sup> )	283	342
Series resistance ( $\Omega \times \mu m^2$ )	3.53	2.92
Cut-off frequency (GHz)	220	337

Table 3. MGA-based optimization.

From Table 3, we can note that the optimized design includes highly doped source-drain extensions and a lower channel doping concentration. Also, the overall MOSFET length is scaled of 12.8 nm, namely 10 nm in the channel region and 1.4 nm in each extension. In principle, the use of highly doped extensions is a technologically feasible approach that requires only an appropriate ion implantation process. At the same time, for the mature technology of Si, the transistor scaling is well addressed to nanoscale devices. Finally, whereas the reference value of the work function is related to the conventional polysilicon, the optimized  $\Phi_m = 4.6$  eV could be obtained by using chromium as gate material [46].

The comparison between the drain current variation with respect to  $V_{gs}$  for the reference device and the MGAbased design is shown in figure 8. Here, three experimental points extracted from the current-voltage characteristics measured in [25] for a GAAJ transistor structure, which is almost similar to the reference device are also reported. The experimental MOSFET presents a channel thickness of 6 nm, a channel length of 50 nm, a oxide thickness of 13 nm, and a uniform donor doping concentration of  $1 \times 10^{19}$  cm<sup>-3</sup>. It was characterized for  $V_{gs}$  up to 1 V showing a comparable threshold voltage level.



Figure 8. Variation of  $I_d$  with respect to  $V_{gs}$  for the reference device and the MGA-based design.

The consistency of the results in figure 8 validates the prediction capabilities of the used analytical model. Also, the optimized GAAJ MOSFET exhibits a drain current higher than that of the reference device in the whole explored  $V_{gs}$  range. In particular, it performs 17% and 54% improvement in series resistance and cut-off frequency, respectively. At the same time, the increase of the SC effects appears rather limited. The proposed optimization technique could be therefore considered as an attractive design strategy.

## 6. Conclusion

A genetic algorithm approach for the design optimization of a GAAJ MOSFET has been presented supporting the calculations of a compact current-voltage analytical model. In fact, fundamental design parameters such as the channel radius, channel length, donor doping concentrations, and oxide characteristics are interrelated geometrical and physical parameters that influence the effective device performance. The drain current, cut-off frequency, and subthreshold slope have been assumed as fitness functions. The MOSFET series resistance has been also calculated in the transition region of the  $I_d$  - $V_{gs}$  curves. The optimized device achieves a cut-off frequency of 337 GHz and a series resistance of 2.92  $\Omega \times \mu m^2$ . By comparing these results with the performance of the reference structure, we can state that the suggested design strategy appears as an attractive practical tool for the design of high-performance GAAJ MOSFETs, offering a reasonable computational time and low complexity. These transistors could be considered well suited for modern radio frequency systems such as signal mixers operating in the gigahertz regime, and frequency multipliers that are widely used in digital/analog communications as well as radio astronomy and terahertz sensing applications.

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